

00862.022239

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:	)	
	:	Examiner: R. A. Jarrett
Shigeyuki UZAWA et al.	)	
	:	Group Art Unit: 2125
Application No.: 09/864,309	)	
	:	Confirmation No.: 2803
Filed: May 25, 2001	)	
	:	
For: EXPOSURE APPARATUS, COATING/DEVELOPING	)	
SYSTEM, DEVICE MANUFACTURING SYSTEM,	:	October 10, 2006
DEVICE MANUFACTURING METHOD,	)	(Tuesday after Federal
SEMICONDUCTOR MANUFACTURING FACTORY,	:	Holiday)
AND EXPOSURE APPARATUS MAINTENANCE	)	
METHOD	:	

**Mail Stop RCE**  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

PRELIMINARY AMENDMENT

Sir:

Prior to further examination on the merits, please amend the above-identified application  
as follows: